

SEP 27 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Hyun-Jae Kim, et al.	)
		) Group Art Unit:
Serial No.:	10/663,081	) 2812
		)
Filed:	September 16, 2003	) Examiner:
		) Isaac, Stanetta D.
For:	MASK FOR POLYCRYSTALLIZATION AND	)
	METHOD OF MANUFACTURING THIN FILM	)
	TRANSISTOR USING	)
	POLYCRYSTALLIZATION MASK	)

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the restriction requirement mailed on August 27, 2004, and in accordance with the provisions under 37 CFR § 1.115 and 1.143, the Applicants submit the following election for further prosecution on the merits:

Election:

The Applicants hereby provisionally elect Group I, claims 1-13, drawn to a product, classified in class 430, subclass 5+.